AV6 0 9 2002		Sheet <u>1</u> 01 <u>3</u>	
C. C	Atty. Docket No. 1074D2	Serial No. 10/075,021	
LIST OF CITATIONS BY APPLICANT (Use several sheets if necessary)	Applicant James J. Finley et al.		
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ATP	AL	2,178,064	2/87	Great Britain				
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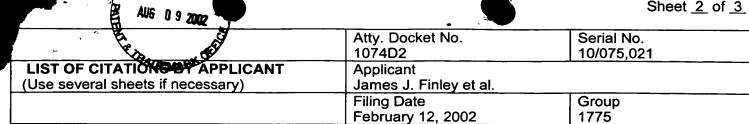
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ATP	AR	Inoue et al., Materials Letters 16 (1993) pp. 181-184, "Nitrogen-induced amorphization in Al ₈₀ Ti ₂₀ films prepared by reactive sputtering"
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^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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ATP	AA	5,062,937	11/91	Komuro	204	192.15	
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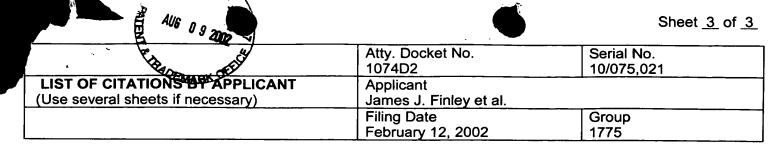
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